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PATENT, TRADEMARK &amp; COPYRIGHT MATTERS

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TECHNOLOGY CENTER 28007 B23

DATE: 13 MAY 2002TIME SENT: 1:12 P.M.TOTAL PAGES (INCLUDING COVER SHEET): 12ATTENTION: M. ESTRADACOMPANY NAME: U.S.P.T.O., ART UNIT # 2823TO FAX NUMBER: (703) 308-7722 (7724, 3431, 3432)

TRANSMITTING FROM: ROSENBERG, KLEIN &amp; LEE

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OUR DOCKET NO. MR1035-820 YOUR REFERENCE 5/N 09/781,283PLEASE NOTIFY US AT ONCE IF NOT RECEIVED PROPERLY.

ADDITIONAL COMMENTS:

AMENDMENT FOR ENTRY

MR1035-820

CERTIFICATE OF FACSIMILE TRANSMISSION

I HEREBY CERTIFY that this Amendment responsive to the 13 February 2002 Office Action is being facsimile transmitted to Art Unit No. 2823 of the U.S. Patent and Trademark Office on the date shown below.

FOR: ROSENBERG, KLEIN &amp; LEE



David I. Klein

Registration No. 33,253

13 May 2002

Date

DIK/dj

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MR1035-820

*#3/Amend a  
of Feb  
5/4/02*IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Jeng et al.

Serial No. 09/781,283

File Date: 02/13/2001

Title: Planarization Method Of Inter-Layer  
Dielectrics And Inter-Metal Dielectrics

: Art Unit No. 2823

: Examiner: M. Estrada

AMENDMENTBox Non-fee Amendment  
Assistant Commissioner for Patents  
Washington, DC 20231

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Sir:

In response to the First Office Action dated 13 February 2002, please enter the following Amendment.

IN THE CLAIMS:

Please replace the following Claims with the clean copies thereof, as follows:

Claim 1 should be replaced with:

1. (Once Amended) A planarization method of inter-layer dielectrics, comprising

*Sub B1*  
the steps of:  
*Alt*